

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Shen et al.	Group Art Unit: 1763
Application No: 09/507,629	Examiner: Allan W. Olsen
Confirmation No: 7912	Attorney Docket No:
Filed: 2/18/2000	001945 USA P 03/ETCH/SILICON/JB1
Title: SELF-CLEANING PROCESS FOR ETCHING SILICON-CONTAINING MATERIAL	September 30, 2003 San Francisco, California

AMENDMENT IN RESPONSE TO FINAL OFFICE ACTION

Commissioner for Patents

Via Facsimile
(703) 872-9311

Examiner Olsen:

This communication is in response to the Office Action mailed on June 4, 2003, and is being timely filed within four months thereof with a request for a one-month extension of time.

Certificate of Transmission	
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By: <u>Stephen Guzzi</u> Stephen Guzzi	Date: <u>September 30, 2003</u>